

SEMI-200MC | 200 mm Semi-Automatic Probe Station For True DC/CV and RF Characterization & Testing of Semiconductor Wafers Devices

4 FEATURES / BENEFITS

- ♣ Motorized X-Y stage assembly with up to
 200mm x 200mm range of motion
- ♣ Motorized Z stage assembly with up to 10mm range of motion.
- Software Capabilities:
 - Screen navigation, wafer mapping, vacuum actuation,
 - Wafer map synchronization,
 - Image capturing through microscope in JPEG format,
 - Feature for setting the separation,

 contact and over travel for safe probing distance, Automated wafer level

 measurement of semiconductor devices,
 - Integrable with semiconductor device analyzer
- **♣** Ready for temperature range -70 °C to 300 °C
- ♣ High quality stereo zoom/compound microscopes with high-intensity LED lighting provide outstanding vision at magnifications. Includes camera port
- **4** Automatic prevention of mechanical contact between lens and probes
- **♣** High resolution Micropositioners
- ➡ Vibration Isolation Table and EMI Shield
- **RF** options available (Up to 67 GHz) include customizable RF probes, RF biasable chuck, and shielding enclosures







SPECIFICATIONS

Chuck XYZ Stage Travel: Motorized

X-Y Travel range		Up to 200 mm x 200 mm
X-Y Stage Speed	•	50mm/Sec (Max)
X-Y Stage Resolution	•	1.0 µm
X-Y Stage Accuracy	•	±2μm
X-Y Stage Repeatability		<3µm
Chuck Z axis adjustment	•	10 mm
Z Stage Speed	•	20mm/Sec(Max)
Z Stage Resolution		0.5µm
Z Stage Accuracy	:	±2μm
Z Stage Repeatability	•	<3µm
Motorized Chuck Theta travel	:	±18°
Theta Resolution	:	0.0018 mm

MICROSCOPE MOVEMENT

	XYZ Programmable	XY manual, Z programmable	XYZ manual
Travel range	50 x 50 mm	50 x 50 mm	50 x 50 mm
Resolution	1 μm	< 5 μm	< 5 µm
Repeatability	< 2 µm	N/A	N/A
Accuracy	< 5 μm	N/A	N/A
Z Travel range	50 mm	50 mm	50 mm
Resolution	0.05 μm	0.05 μm	N/A
Repeatability	< 2 μm	$< 2 \mu m$	< 2 µm
Accuracy	< 4 μm	$< 4 \mu m$	N/A

PLATEN:

Specifications:

Platen Material	: Stainless Steel
Manual Platen Travel	: 10 mm
Max. No of Micro-Positioners	: 10, (Up to 6 DC and 4 RF) or 4.5" Probe Card
Clearance space	: ≥ 5 mm (between probe card holder and platen)
Micropositioners Mounting	: Compatible for both Magnetic as well as Vacuum base Micropositioners
RF Micro-Positioner mounting	: Magnetic/Vacuum base with guided rail
DC Micro-Positioner mounting	: Magnetic/Vacuum base



NON-THERMAL CHUCKS

Stan	dard	Wafer	Chucl	z•
Duan	uaiu	vvaici		Λ.

Chuck Connections : Coaxial (BNC)/ Triaxial

Chuck Diameter : Up to 200 mm

Chuck Material : Stainless Steel. Chuck made of other material is

available as optional

Chuck surface : Planar with centric engraved vacuum grooves

Vacuum actuation : Manual/Software Actuation

Sample Size : Min 5mm x 5mm up to 200 mm wafer

Chuck Surface Planarity : $10\mu m$, Optional down to $\pm 3\mu m$

RF Wafer Chuck:

Chuck Connections : Coaxial (BNC)

Chuck Diameter : Up to 200 mm 2 AUX chuck as optional

Chuck Material : Nickel Plated aluminum

Chuck surface : Planar with centric engraved vacuum grooves

Chuck Sample actuation : Vacuum actuation with three zone vacuum holes

Sample Size : Min 5mm x 5mm up to 200 mm wafer

Chuck Surface Planarity : 10μm, Optional down to ±3μm

Auxiliary Chuck:

Quantity : 2 Nos of AUX Chuck

Chuck Diameter : Up to 20 mm

Chuck Material : Derlin, RF absorbing material

Chuck Sample actuation : Separate vacuum control switches for auxiliary chucks

Sample Size : Min 5mm x 5mm up to 200 mm wafer

Chuck Surface Planarity : 10μ m, Optional down to $\pm 3\mu$ m

LECTRICAL SPECIFICATIONS:

Standard Chuck @10 V:

Parameter	Coaxial Chuck	Triaxial Ch	nuck
Operation Voltage /Breakdown Voltage	Up to 1.5K V DC	Up to 1.5K \	V DC
Isolation	$> 2 \text{ G}\Omega$	Chuck isolation	$> 100 \mathrm{G}\Omega$
		Force to guard	$> 100 G\Omega$
		Guard to shield	$> 10 \text{ G}\Omega$
		Force to shield	$> 50 \text{ G}\Omega$
Leakage current	< 50pA	≤ 50fA	
Capacitance	< 800pF	< 100fF	7
Chuck Flatness	≤10μm	≤10μm	



THERMAL CHUCK:

Parameter	Coaxial Chuck	Triaxial Chuck
Temp. Control Method	Resistive type heating	Resistive type heating
Thermal Management	Air cooling/Water cooling	Air cooling/Water cooling
Temperature Range	RT - 200°C, Optional up to 600°C	RT - 200°C, Optional up to 600°C
Temperature Control	Linear DC/PID	Linear DC/PID
Heating & Cooling Time	Heating and cooling from RT to 20 Heating and cooling from RT to 30	
Temperature Sensor	Thermal couple	Thermal couple
Temperature Stability	±0.5 °C	±0.5 °C
Temperature Accuracy	±1 °C	±1 °C
Temperature Uniformity	< 1.5 °C	< 1.5 °C
Connection Interface	RS485	RS485
Chuck Surface Plating	Nickel/Gold	Nickel/Gold
Surface Flatness	$\pm 10 \mu m@RT \& \le 30 \mu m@ \ge 300^{\circ}$	$\pm 10 \mu m@RT \& \le 30 \mu m@ \ge 300$ °C
Leakage Current	< 100pA	<100fA
Capacitance	≤ 800pF	≤ 100pF

4 TRIAXIAL HOT&COLD CHUCK

Temperature Range	-70 °C to 300 °C		
Connectivity	Kelvin Triax		
Temperature control Method	Air Cooling / Water cooling/ Resistive heater		
Smallest temperature Selection step	0.1 °C		
Temperature resolution	0.01 °C		
Temperature stability	±0.08 °C		
Temperature accuracy	0.1 °C		
Interfaces	RS232C		
Chuck surface plating	Nickel plated		
Temperature Accuracy	$< \pm 0.5$ °C at ≤ 100 °C		
	$<\pm1.0$ °C at > 100 °C		
Surface flatness	$< \pm 10 \ \mu m \ at \le 200 \ ^{\circ}C$		
-70°C	< 30 fA		
-40°C	< 30 fA		
-10°C	< 30 fA		
25°C	< 15 fA		
200°C	< 30 fA		
300°C	< 50 fA		
Capacitance	~pF		



MICRO CHAMBER

EMI shielding : >20 dB 0.5-20 GHz

Spectral noise floor : <-150 dBVrms/rtHz

System AC noise : <15 mVp-p

MICROPOSITIONERS:

Model	Description		Electrical Specifications
MH100	Fixed Magnet Base Switchable Magnet Ba Vacuum Base	ase	
MH100	Foot dimension Travel range X,Y Travel range Z Feature Resolution TPI resolution	70 x 50mm 12mm 12mm 1µm/0.8µm 80 TPI/100TPI	 Operation voltage up to 3KV Current measurement PA to A Pulsed Capacitance measurement pF to μF
MH200	Fixed Magnet Bas Switchable Magne Vacuum Base		
MH200	Foot dimension Travel range X,Y Travel range Z Feature Resolution TPI resolution	70 x 50mm 12mm 12mm 0.83µm 85 TPI	 Operation voltage up to 3KV Current measurement PA to A Pulsed Capacitance measurement pF to μF
MH300	Fixed Magnet Base Switchable Magnet Ba Vacuum Base	ase	
MH300	Foot dimension Travel range X,Y Travel range Z Feature Resolution	70 x 35mm 12mm 12mm 5µm	 Operation voltage up to 3KV Current measurement PA to 40A Pulsed Capacitance measurement pF to µF
MH500	Switchable magnet ba Vacuum Base	se	·
MH500	Foot dimension Travel range X, Y Travel range Z Feature Resolution	80 x 90mm ±15 mm ±15 mm 3µm	 Operation voltage up to 3KV Current measurement PA to A Pulsed Capacitance measurement pF to μF

♣ Probe Tip Holders with Connecting Cable:

Model	Description			
	Coaxial Tip Holder with Coaxial Cable			
SHC15	IC15 Spring Holder/1.5m coax cable/BNC male			
THC15	Tube Holder/1.5m coax cable/BNC male			
NHC15	Nut Holder/1.5m coax cable/BNC male			
Triaxial Tip Holder with Triaxial Cable				
THT15	THT15 Tube Holder/1.5m Triax cable/Triax male			
NHT15	Nut Holder/1.5m Triax cable/Triax male			
High Frequency Probe Arms				
MWA-EW	HF probe arm (east-west)			
MWA-NS	HF probe arm(north - south)			





Luxury Anti-vibration table

Vibration isolation Table

Active Vibration Isolation

Antistatic surface

Come with retractable casters

Could sit in front of table

Screen holder for two monitor and keyboard drawer

Natural frequency 3-5Hz

Dimension W1200xD1200xH750mm

Load Capacity: ≥ 300Kg